

ABSTRACT

The present invention relates to a substrate-holding device including a mask member, a biaser, and a contact part. A contact member is provided with an inclined surface, an extending surface, and an abutting surface. A substrate is positioned by bringing the substrate, which is in a state of being biased by the biaser, and the mask member closer to each other in a first direction, guiding an outer edge section of the substrate to the abutting surface side along the inclined surface, and then causing the abutting surface to abut against the outer edge section of the substrate.

Figure 13